

Chemical induced porosity on BiVO_4 films produced by double magnetron sputtering to enhance the photo-electrochemical response

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Supporting Information

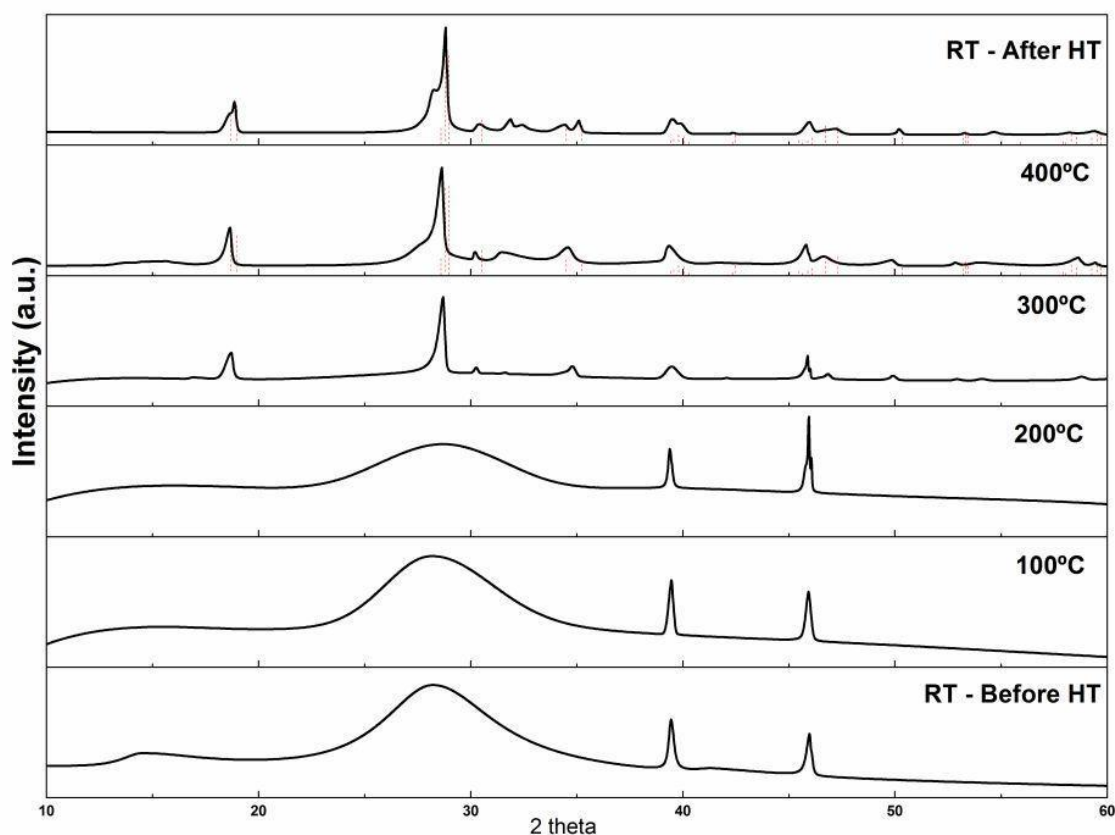


Fig S1: XRD profile of BiVO_4 film made by DMS under in-situ temperature increase analysis. RT stay for the XRD patterns obtained at room temperature, before and after the heat treatment (HT).

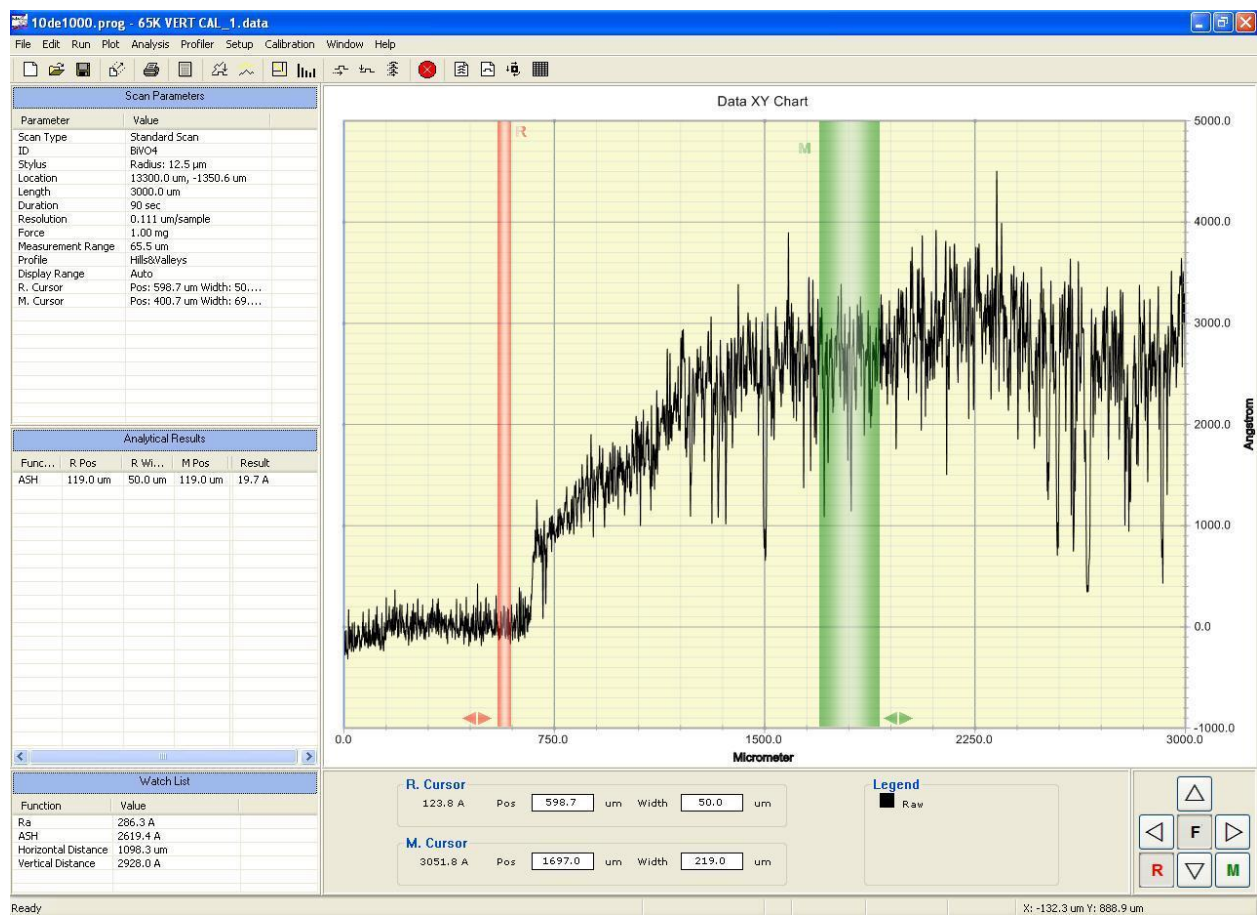


Fig S2: Profilometric measurement of the BiVO₄ film after the KOH treatment.